M2 Beam

M² laser beam propagation analyzer



Combines all ISO compliance accuracy

Flexible, with different versions for pulsed and CW lasers Special version for high power measurements up to 4 kWatt Removable measuring head for

regular laser beam profiling

Specifications

Input Beam

	M2Beam	M2Beam U3
Technology	Multi knife-edge scanning with silicone detector, InGaAs detector and enhanced InGaAs	USB 3 with CMOS 2.4 MP and built in filter wheel
Spectral Range (nm)	350 - 1100 for Si version 800 - 1800 for InGaAs version 190 - 1100 for UV- Enhanced version 1200 – 2700 for InGaAs enhanced version	220 – 1350 with built in special CMOS technology
Beam Power Range	100 μW – 1W (with supplied internal filters for the Si version) 100 μW – 5 mW for InGaAs & UV versions Up to 4 kW for HP version	10 μW – 100 mW with built in filter wheel Up to 4 kW for HP version
Number of Knife-edges	7	
Beam Size	Up to 25mm diameter with lens (Si&UV versions)	
Beam Waist to Lens Distance	2.0 to 2.5 meters optimum 2.0 meters minimum	

Scanning Assembly Attachment

Construction	Aluminium
Lens Focal Length	300 mm (at 632.6 nm)
Lens Diameter	25 mm
Number of Scan Steps	140
Minimum Step Size	100 μm
Scan Length	280 mm

Physical

Weight	2.5 Kg
Dimensions	100 x 173 x 415 mm
Mounting	M6 or ¼" screws
Mechanical Adjustment	Horizontal angle: ±1.5° Vertical angle: ±1.5°
Cable Length	2.5 m

Accuracy:

M² Values & General Parameters Accuracy: ±5%

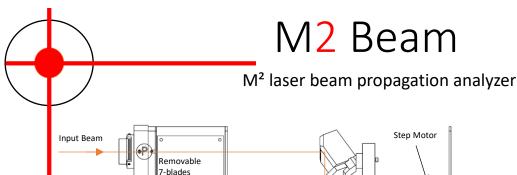




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December 2024

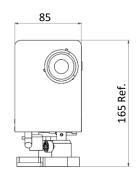


150 mm Travel

Lead Screw

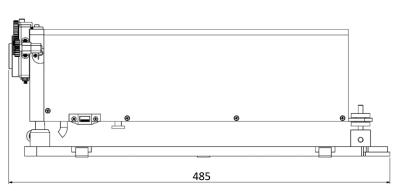
beam

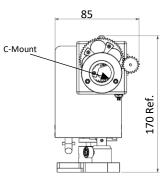
profiler

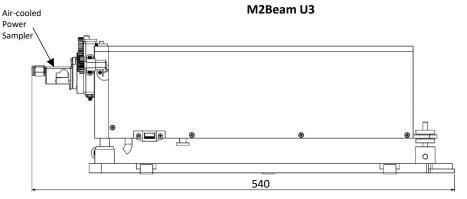


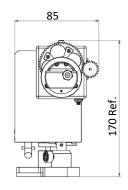
M2Beam

465









M2Beam U3 High Power

Ordering Information

Knife-Edge Versions:

M2Beam-Si – measurement device for silicon range (350 – 1100 nm)

M2Beam-UV - measurement device for silicon range (190 - 1100 nm)

M2Beam-IR - InGaAs measurement device (800 - 1800 nm), Select IR3/IR5 Sensor

M2Beam-IR3E - InGaAs Enhanced measurement device (1200 - 2700 nm)

Camera Version:

M2Beam-U3 - Measurement device for silicon range (350 - 1100 nm)

Measurements: Beam Propagation (M2) **Beam Waist Location** Beam Waist Diameter Divergence Rayleigh Range Waist Asymmetry Astigmatism



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